



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Koichi KANAYA et al.

Group Art Unit: 1709

Application No.: 10/565,653

K. CHEN

Filed: January 24, 2006

Examiner:

Docket No.: 126247

VAPOR DEPOSITION APPARATUS AND VAPOR DEPOSITION METHOD

AMENDMENT UNDER 37 C.F.R. §1.111

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

For:

In reply to the May 2, 2007 Office Action, the period for reply being extended by the

Petition for Extension of Time filed herewith, please consider the following:

Amendments to the Claims as reflected in the listing of claims; and

Remarks.